

**COMPARATIVE STUDY FOR THREE DIFFERENT  
STRUCTURES OF THE P-N JUNCTION ON SILICON (111)  
WAFER.**

**AMIRUL AIMAN BIN AHMAD HISHAM**

**2008407722**

**Final Year Project Submitted in Partial Fulfillment of the  
Requirements for the Bachelor of Science (Hons.) Industrial  
Physics in the Faculty of Applied Science  
Universiti Teknologi MARA**

**APRIL 2011**

## **Acknowledgement**

First of all, I would like to express my gratitude towards my supervisor, Miss Farah Liyana, for her tireless efforts and on-going support, advice as well as guidance, which without those helps, this project would not have been completed successfully.

I also would like to extend my heartiest gratitude to my family especially my parents, Ahmad Hisham Bin Maarof and Hasnah Binti Kamaruddin for their moral and financial supports, and also for always been there with me through thick and thin. They were also the source of strengths that keeps me working hard without giving up to complete this final year project. And also to all my friends and individuals who offer needed tips, advice and endless cooperation. Kindness of each one of the individuals mentioned above will always be remembered.

Finally, I hope that this report will give the readers some insight to the process of p-n junction fabrication and the best structure to fabricate it.

**Amirul Aiman**

## TABLE OF CONTENTS

<b>APPROVAL SHEET</b>	<b>I</b>
<b>ACKNOWLEDGEMENT</b>	<b>II</b>
<b>LIST OF TABLES</b>	<b>III</b>
<b>LIST OF FIGURES</b>	<b>IV</b>
<b>ABSTRACT</b>	<b>VIII</b>
<b>ABSTRAK</b>	<b>IX</b>
<b>CHAPTER 1 INTRODUCTION</b>	
1.1 Introduction	1
1.2 Structure of Solid Material	2
1.3 Crystal Orientation	4
1.3.1 (100) And (111) Wafers	5
1.3.2 Wafer Flats	5
1.4 Doping	7
1.5 Energy Band	7
1.6 P-N Junction	11
1.6.1 Forward Bias	12
1.6.2 Reverse Bias	13
1.7 Problem Statement	14
1.8 Significance of Study	14
1.9 Objective of Study	14
<b>CHAPTER 2 LITERATURE REVIEW</b>	
2.1 Structures	15
2.1.1 P-N Junction Terminated with Diamond	15
2.1.2 Passivated P-N Junction in Mesa Semiconductor Structure	17
2.2 Methods and Techniques of Diffusion	19
2.3 Electrical Characterization	21

## **Abstract**

This project is about a comparative study for 3 different structures of the p-n junction on Silicon (111) wafer. A study about p-n junction was important since it serves as a basis on understanding other semiconductor devices that play a major role on modern technology development nowadays. P-N junction was actually formed by locating the p-type and n-type semiconductors together. And to achieve this, a process called doping was used. Doping is a process which introduces impurities into an intrinsic semiconductor to change its electrical characteristic either by ion implantation, diffusion of dopant, or epitaxy techniques. But in this project, it would be only concentrated on diffusion of dopant since it is the most convenient way. While for the locating the p-type and n-type semiconductors together, there were actually several possible arrangements or structures of locating the p-type and n-type. Based on that idea, this project will investigate the electrical characteristics of each type of the three structures that had been planned to be fabricated, the differences, and the most ideal structure to fabricate a p-n junction. The method that will be used in fabricating the p-n junction is the same as the basic method in fabricating a p-n junction process except for the lithography process since there will be three different structures of the p-n junction that will be going to be fabricated. Thus the mask used will be different from each structure. And as for the result, it will be obtained by current-voltage (I-V) measurement. From that data, electrical characteristics for each structure, the differences and the most ideal design structures for making a p-n junction can be concluded. After the project had been completed, it shows that structure 3 with large dimension (sample 6) was the best structure for p-n junction fabrication.

# CHAPTER 1

## INTRODUCTION

### 1.1 Introduction

Terms of 'semi' means half, while 'conductor' refers to a material or device that conducts or transmits heat or electricity, especially, when regarded in terms of its capacity to do this[1]. Both terms, if combined will give one general meaning of 'semiconductor', which is; a material that has about half of the ability to conducts or transmits electricity. On the other hand, if a material does not have the ability to conducts or transmits electricity it will be called as an insulator. But since the semiconductor material has only half of the ability of a conductor, semiconductor can also be categorized as an insulator. Based on these ideas, a rough conclusion can be made, which is, semiconductor is a material that have both characteristic of conductor and insulator.

Scientifically, semiconductor is a material that has an electrical conductivity due to electron flow which is intermediate in magnitude between a conductor and an insulator. The reason why this kind of material does have both characteristic is that their crystal lattice is modified by introducing impurities or known as dopant into the crystal lattice[2]. This process is called doping. A pure semiconductor before introducing an impurity is called 'intrinsic semiconductor' while semiconductor that had been introduced with impurity is called 'extrinsic semiconductor' [3]. Interesting fact related to the semiconductor and the doping technique is, the magnitude of the conductivity and the electrical characteristic of the semiconductor material can be altered by controlling the amount of dopant that is going to be introduced into the crystal lattice. After the amount has been decided, semiconductor devices such as diode, transistor, sensor, etc can be fabricated.